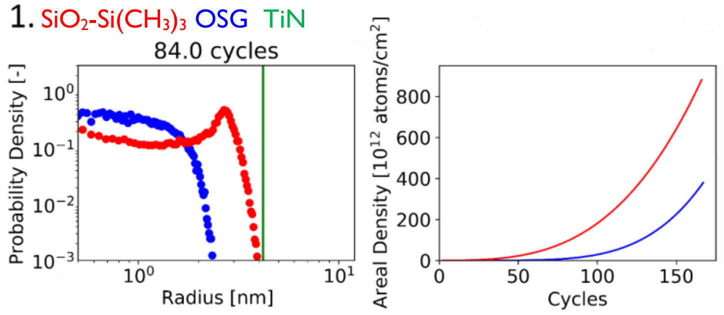
1.



2.

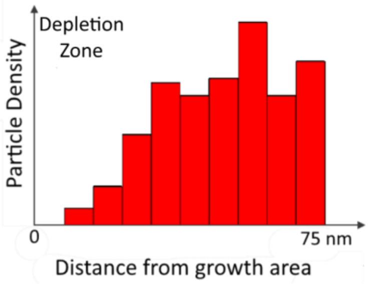


Figure 1. Simulated particle size distribution at 84 cycles and Ru areal density at 1-167 cycles for EBECHRu ALD (325°C) on SiO_2-$Si(CH_3)_3$ and OSG surfaces. The green line denotes the equivalent Ru film thickness on a TiN growth surface.

Figure 2. Particle density on OSG non-growth surface area as a function of distance from the interface with the growth area.